

Title (en)
METHOD FOR TREATING SUBSTRATES WITH CHEMICALS

Title (de)
VERFAHREN ZUM BEHANDELN VON SUBSTRATEN MIT CHEMIKALIEN

Title (fr)
PROCÉDÉ DE TRAITEMENT DE SUBSTRATS AVEC PRODUITS CHIMIQUES

Publication
EP 4122006 A1 20230125 (DE)

Application
EP 21707631 A 20210217

Priority

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- EP 2021053867 W 20210217

Abstract (en)
[origin: WO2021165308A1] According to the invention, when treating substrates with a treatment medium containing at least one chemical effective for treatment, for example when removing a masking layer (101) from a semiconductor substrate (110) by etching, the treatment medium is heated to a temperature effective for treatment only immediately prior to apply to the substrate (110), the treatment medium being at the optimum temperature for treatment when it impinges on the substrate. Thus, a short treatment time, low, thermally induced decomposition losses of chemical and a saving of treatment medium are achieved.

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Citation (search report)
See references of WO 2021165308A1

Designated contracting state (EPC)
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